



XA-9387  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183

Group Art Unit: 2877

Filed: November 17, 2000

Examiner: R. Punnoose

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING  
METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME  
MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING  
THE SAME MEASURING METHOD, AND EXPOSURE METHOD

Allowed: December 15, 2003

Confirmation No.: 5906

AMENDMENT UNDER 37 C.F.R. § 1.312

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Attn: Mail Stop Issue Fee

Sir:

Applicant respectfully requests that the above-  
identified application be amended further as indicated  
below.

Amendments to the specification begin on page 2 of this  
paper.

Remarks begin on page 3 of this paper.